

IN THE SPECIFICATION:

Please amend the Specification as follows:

Paragraph [0012] beginning on Page 4, at prenumbered line 11, has been amended as follows:

[0012] Please refer to FIG. 2, which is a schematic diagram of the structure and position of a gauge damper in accordance with a preferred embodiment of this invention. The structure of the gauge damper 5 is formed by assembling at least one plate 41 such as a stainless steel plate in a vacuum tube 4 used to connect the gauge 2 with the chamber 1. The plasma particles flowing from the chamber 1 through the vacuum tube 4 are firstly deposited and attached onto the plate 41 and will not directly impact the sensor 22 of the gauge 2. Hence, the damper 5 has the buffer function. Two plates are exemplified in FIG. 2 and respectively mounted in a substantially vertical position at the upper inner wall and the lower inner wall of the vacuum tube 4 (perpendicular to the flowing plasma particles) such that the pathway of the plasma gas flowing from the chamber 1 through the vacuum tube 4 is of S shape as shown by the arrow and the buffer effect is enhanced.